

Title (en)

METHOD AND MICROMECHANICAL COMPONENT

Title (de)

VERFAHREN UND MIKROMECHANISCHES BAUELEMENT

Title (fr)

PROCEDE ET COMPOSANT MICROMECHANIQUE

Publication

**EP 1546027 A2 20050629 (DE)**

Application

**EP 03717116 A 20030227**

Priority

- DE 0300630 W 20030227
- DE 10244785 A 20020926

Abstract (en)

[origin: WO2004028956A2] Disclosed are a production method and a micromechanical component, in which porous silicon (106) is used as a sacrificial layer and a functional layer (130) is exposed by etching away the sacrificial layer.

IPC 1-7

**B81B 3/00**

IPC 8 full level

**B81B 3/00** (2006.01)

CPC (source: EP US)

**B81C 1/00476** (2013.01 - EP US); **B81B 2201/12** (2013.01 - EP US); **B81B 2203/0118** (2013.01 - EP US); **B81C 2201/0109** (2013.01 - EP US); **B81C 2201/0115** (2013.01 - EP US)

Citation (search report)

See references of WO 2004028956A2

Designated contracting state (EPC)

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DOCDB simple family (publication)

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